Effect of thinning and backplane processing on charge collection properties of irradiated CMOS detectors

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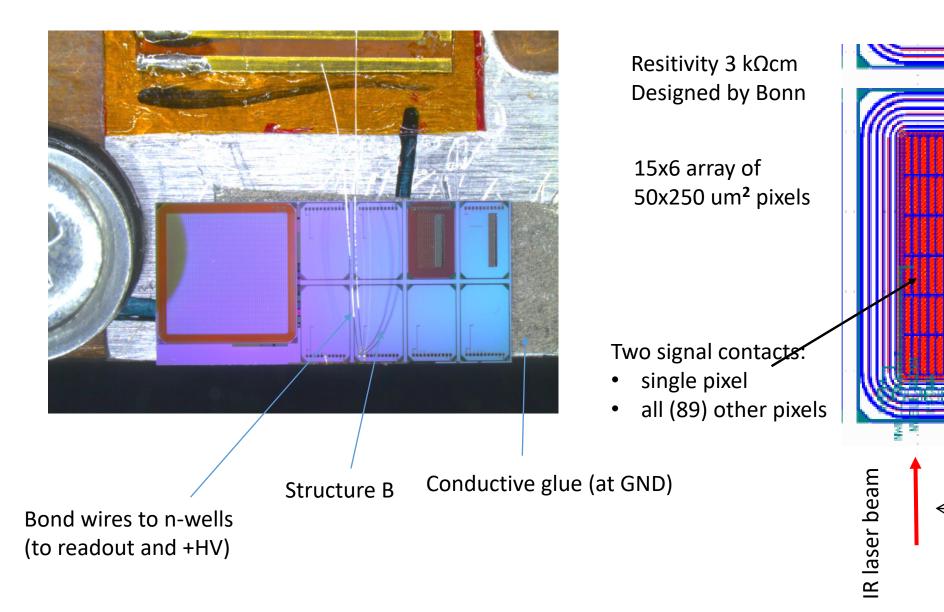
Samples

- test structures from LFoundry demonstrator submission designed by University of Bonn:
 - Piotr RYMASZEWSKI et al., Prototype Active Silicon Sensor in 150nm HR-CMOS technology for ATLAS Inner Detector Upgrade, 2016 JINST 11 C02045
 - T. Wang et al., Development of a Depleted Monolithic CMOS Sensor in a 150 nm CMOS Technology for the ATLAS Inner Tracker Upgrade, <u>2017 JINST 12 C01039</u>
- 150 nm HR-CMOS technology
- resistivity of p-type substrate > 2 kΩcm
- breakdown voltage from 175 V to over 400 V, depending on the test structure
- measurements shown here with passive pixel array
- Two sets:

→ not thinned (700 um), no back plane, substrate biased over implant on top
 → thinned to ~200 um, back plane processed, bias through the BP

- Samples irradiated with neutrons in TRIGA reactor in Ljubljana
- E-TCT and Sr-90 charge collection measurements

LFoundry passive test structure B



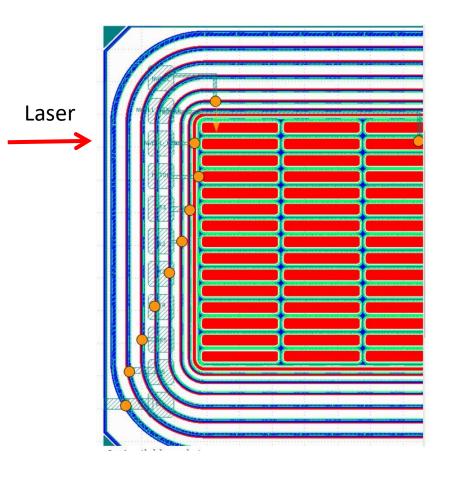
 \odot

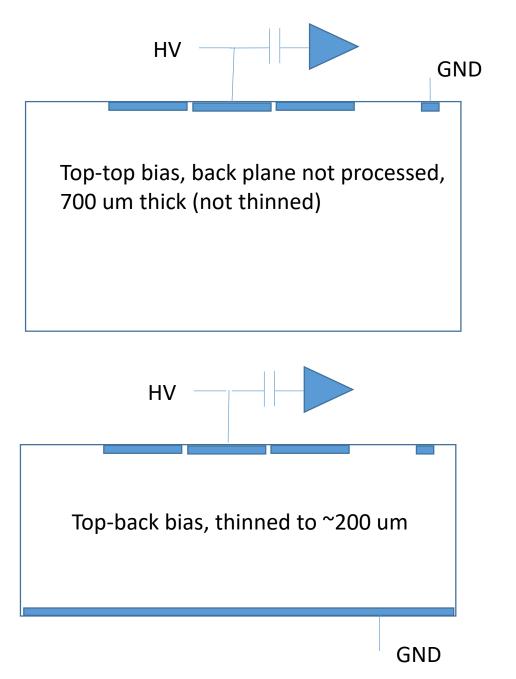
 \rightarrow

y-scan

x @ pixel ~centre

LFoundry passive test structure B

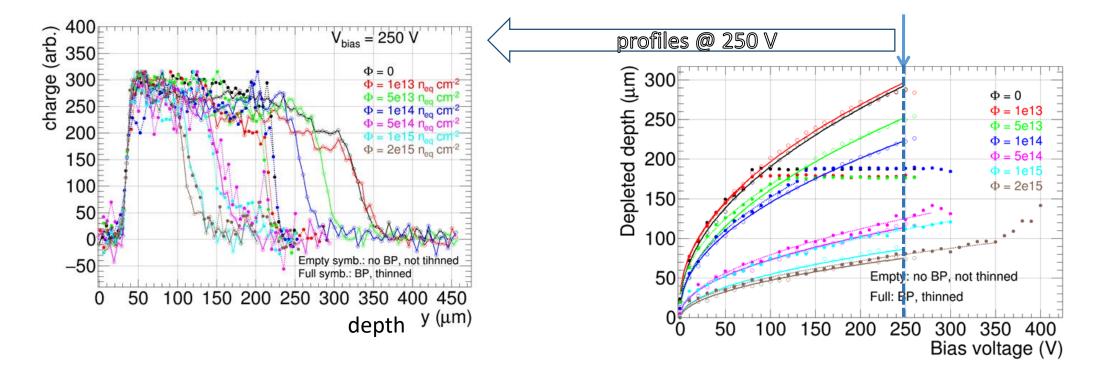




- <u>http://arxiv.org/abs/1801.03671</u>, submitted to NIM A
- RD50 workshop in Krakow

https://indico.cern.ch/event/637212/contributions/2608669/attachments/ 1471691/2277507/RD50_June_2017_IM.pdf

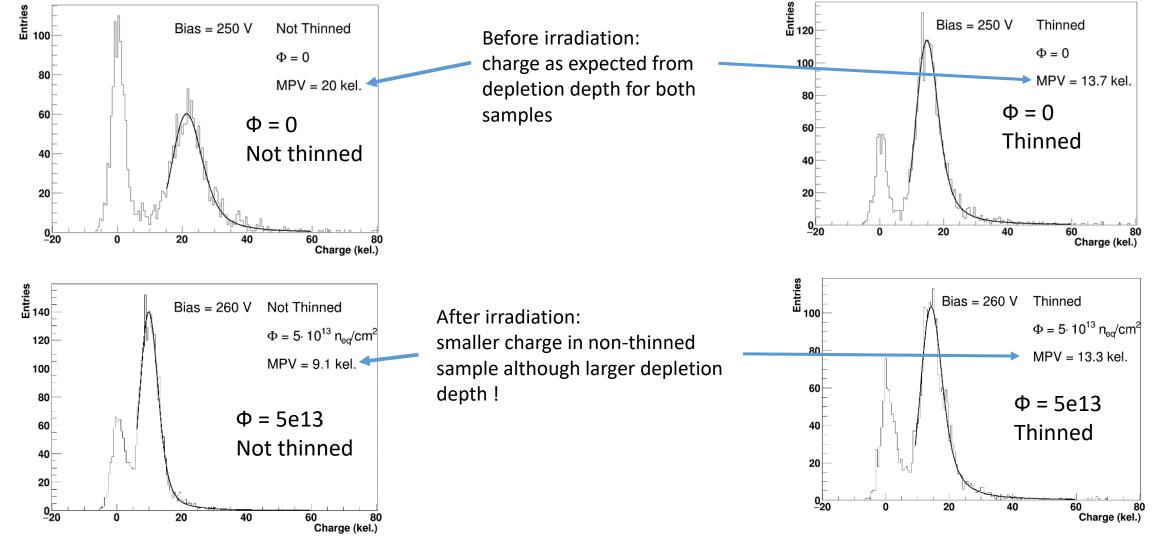
- Charge profiles at different fluences
- Depletion depth estimated from width of the profile



• Charge profiles normalized to same maximum (laser beam monitor not used) !

Charge collection measurements with Sr-90 Ortec 142 + 25 ns shaper





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fully depleted

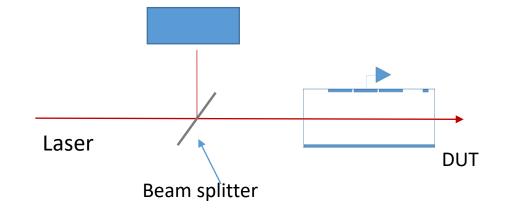
~180 µm thick

E-TCT: beam monitor

Reference detector

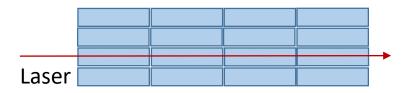
1) use beam monitor:

- \rightarrow can compare signals between detectors
- \rightarrow but still don't know the charge



2) Two readout configurations:

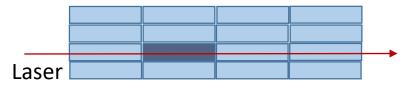
•all pixels connected together to the readout amp



Weighting field as in Sr-90 measurements → similar to pad detector

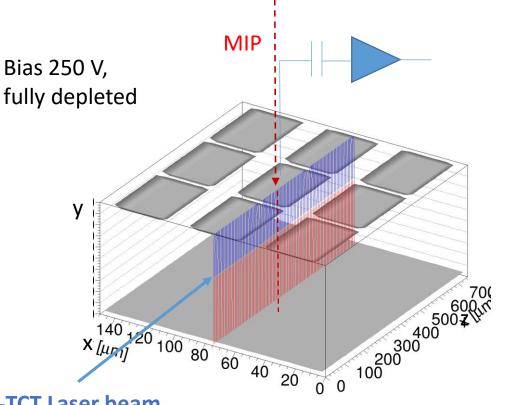
•single pixel

(remaining pixels on same potential but not connected to readout)



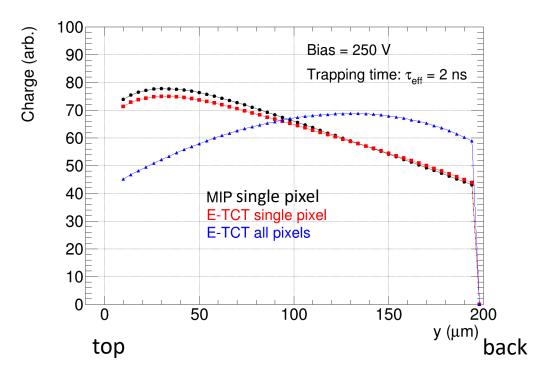
More similar to pixel detector in tracking application but:
 → charge generated and drifting also bellow neighbor pixels affects the induced current pulse on the readout pixel

KDetSim simulation (kdetsim.org)



E-TCT Laser beam

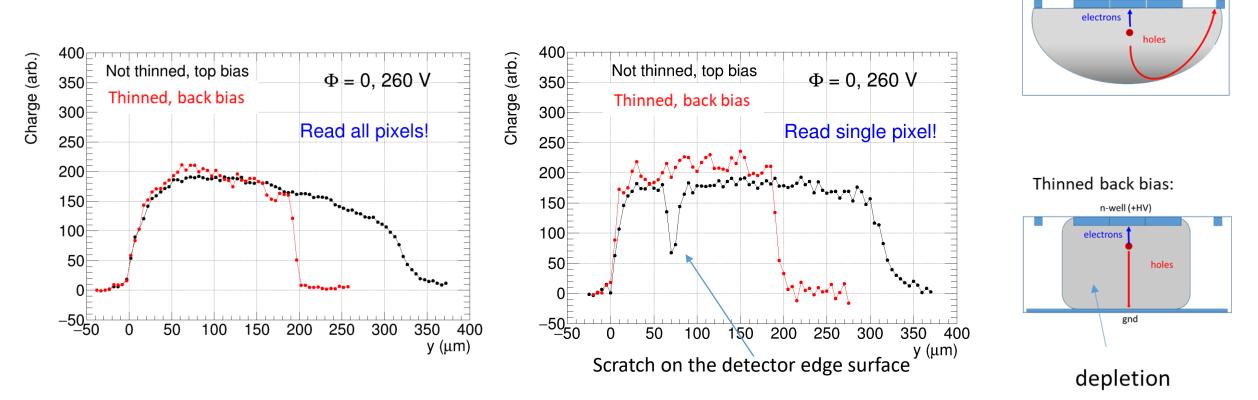
- → MIP vertical impact through the center of readout pixel
- → E-TCT charge carriers drift under several pixels



- charge profile in irradiated detector depends on readout configuration (weighting field)
- E-TCT with single pixel readout similar to MIP profile
 → charge drifting to neighbour pixels doesn't contribute much

E-TCT measurement before irradiation

Charge measured with different samples (i.e. red and black in same plot) normalized to same laser power → possible because of laser beam monitor



- same response at same depth for thinned and not thinned (up to the thickness of thin sample)
- all charge collected in 25 ns at all **y** in both sample

 \rightarrow carriers must drift across whole weighting field \rightarrow obvious in thinned fully depleted sample with back bias

→ not thinned top bias: ohmic conductivity of undepleted substrate sufficient to bring low weighting potential near depletion region

Not thinned top bias:

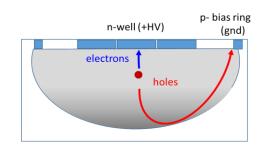
n-well (+HV)

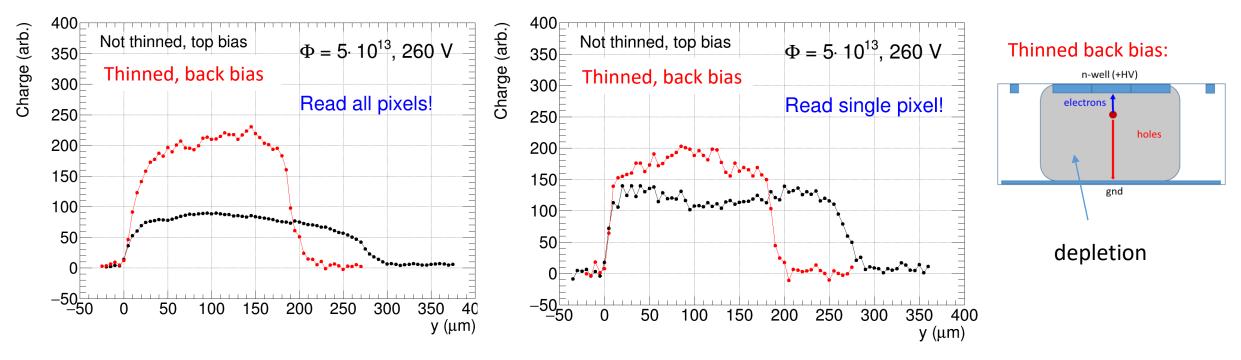
p- bias ring

E-TCT measurement after irradiation:

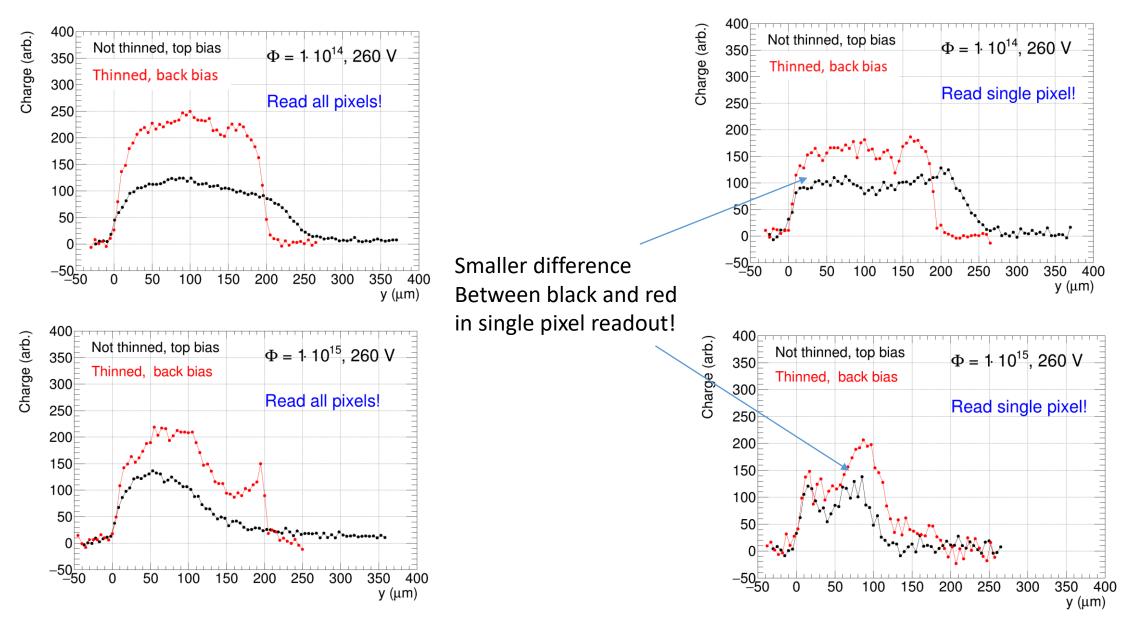
- more charge collected in thinned back-biased sample
 - → in top bias case charge doesn't traverse all weighting field
 - ightarrow trapped in the low field region
- difference looks smaller in single pixel case
 - weighting field peaked near the pixel, drift close to n-well contributes more to collected charge

Not thinned top bias:



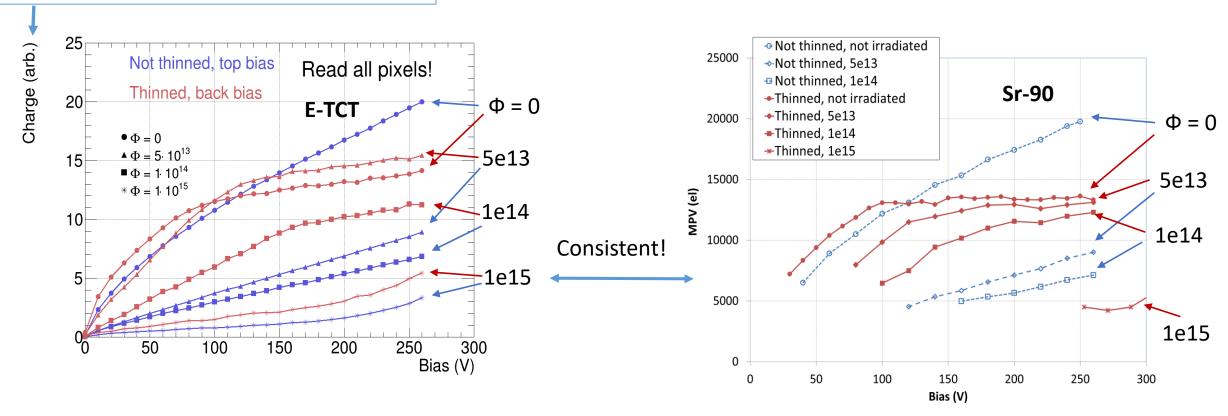


E-TCT, higher fluences



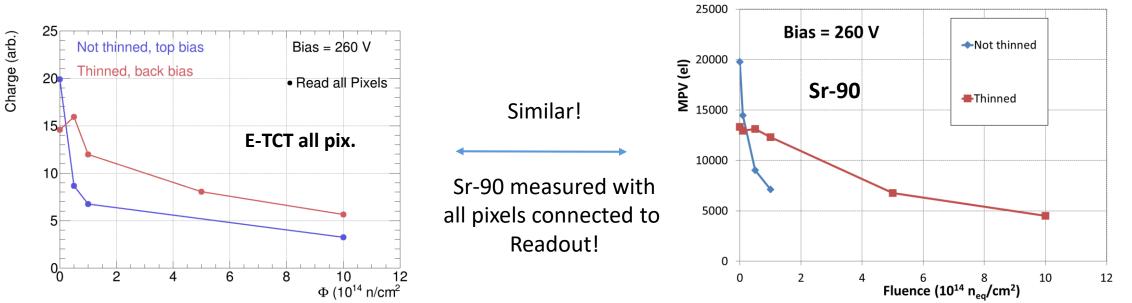
Compare E-TCT with Sr-90 source measurements

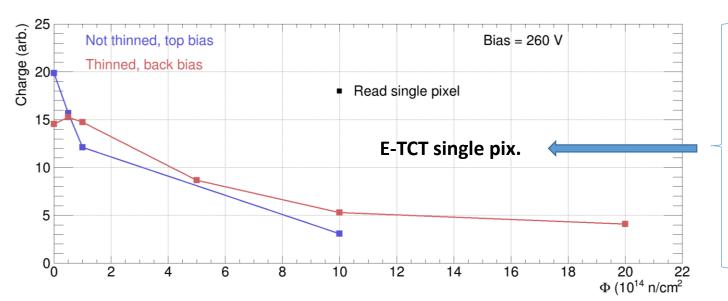
- in source measurements charge is generated along the depth of the detector
 - → Integrate E-TCT charge profile along y (depth) to get a value comparable with charge measured with Sr-90



Integral of charge collection profile along *y*

Charge Vs. fluence at 260 V



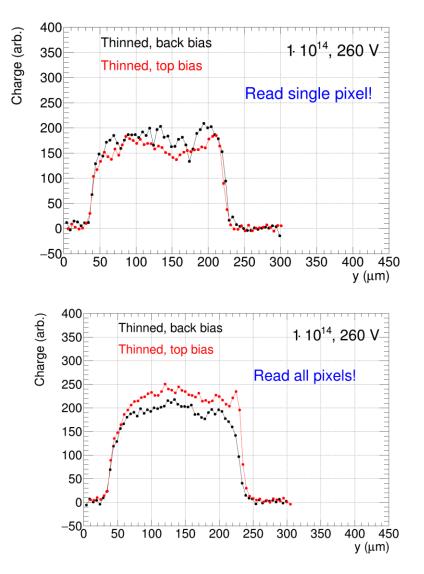


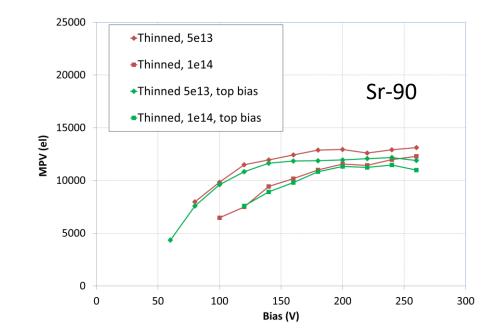
- smaller charge drop in not thinned sample at lower fluences in "single pixel" than in the "all pixel" configuration
- "single pixel" measurement closer to the behavior of real pixel detector in the experiment
 - → single pixel measurements with Sr-90 difficult because pixels are small
 - \rightarrow test beam needed for MIP response

I. Mandić, 32nd RD50 Workshop, Hamburg, Germany, June 2018

Backplane but top bias

 Thinn with back plane but substrate biased via implant on top as in non-thinned samples (sample mounted on kapton → no contact of backplane with support)





Small difference between top and back bias also when not fully depleted!

- contact with back plane via edge of the device
- equipotential plane at the back
 - -> modifies electric and weighting field

Summary

- charge collection properties of depleted CMOS structures studied with E-TCT using beam monitor
 compare E-TCT measurements with different samples at same laser beam intensity
- study charge collection profiles at different fluences and compare two detector sets and readout configurations
- good agreement of E-TCT and Sr-90 source measurements
 - → thinning and backplane improves charge collection after irradiation
 → better charge collection also if backplane floating and substrate contacted from top
 - → effect less significant in "single pixel" configuration because of weighting field (small pixel effect)
 - charge collection estimated with E-TCT in "single pixel" readout should give good estimate for tracking application and it is much simpler than test beam measurement